

Press release

## Heidelberg Instruments Mikrotechnik GmbH – the new investment by RAG-Stiftung

- RAG-Stiftung acquires laser lithography manufacturer in Heidelberg
- Dr. Helmut Linssen evaluates it as an investment with promising future outlook

**Essen/Heidelberg, February 25, 2015. RAG-Stiftung announced the execution of an agreement under which RAG-Stiftung Investment Company acquired 100 percent of Heidelberg Instruments Mikrotechnik GmbH, a leader in design, development, and manufacturing of laser and maskless lithography systems. The agreement was concluded last January, for an undisclosed amount.**

According to Dr. Helmut Linssen, CFO of the RAG-Stiftung, Heidelberg Instruments, a highly specialized company in the field of laser lithography technology, is another investment with great prospects for the future. The Heidelberg technology, its market segment and expertise fit well into the investment strategy of the RAG-Stiftung, which is planning to invest into specialized, medium-sized companies in the fields of mechanical engineering, automation and industrial technologies, serving international growth segments.

Martin Wynaendts, CEO of Heidelberg Instruments, outlined that the agreement with RAG-Stiftung is a compelling strategy that will benefit the company, its employees, and its existing as well as potential customers. Upon this agreement, Heidelberg Instruments will be ideally positioned to compete for major, complex projects across a diverse range of technology and geographical market segments by introducing disrupting technologies in the fields of maskless lithography and the semiconductor industry in the near and medium term time-frame.

Both parties have outlined that current management of Heidelberg Instruments will continue to lead the company.

### **About Heidelberg Instruments GmbH:**

With an installation base of over 600 systems in more than 50 countries, Heidelberg Instruments Mikrotechnik GmbH is a world leader in production of high precision maskless lithography systems. Due to their flexibility, these systems are used in research, development and industrial applications for direct writing and photomask production by some of the most prestigious universities and industry leaders in the areas of MEMS, BioMEMS, Nano Technology, ASICs, TFT, Plasma Displays, Micro Optics, and many other related applications.

For more information, please visit <http://www.himt.de>

**About the RAG-Stiftung:**

The private-law RAG-Stiftung was established in 2007. The RAG-Stiftung's business model aims to ensure the financing of perpetual obligations (Ewigkeitslasten) of RAG's coal mining activities in the German Ruhr and Saar regions by the end of 2018.

For more details on the RAG-Stiftung, please visit [www.rag-stiftung.de](http://www.rag-stiftung.de)

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